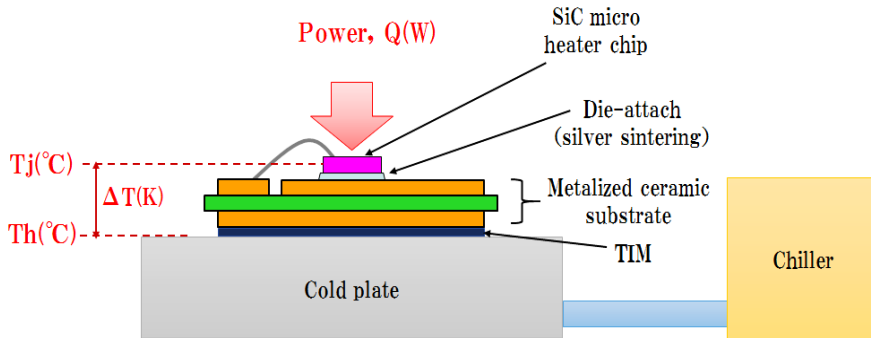


The system of measurement R_{th} of metalized ceramic substrates

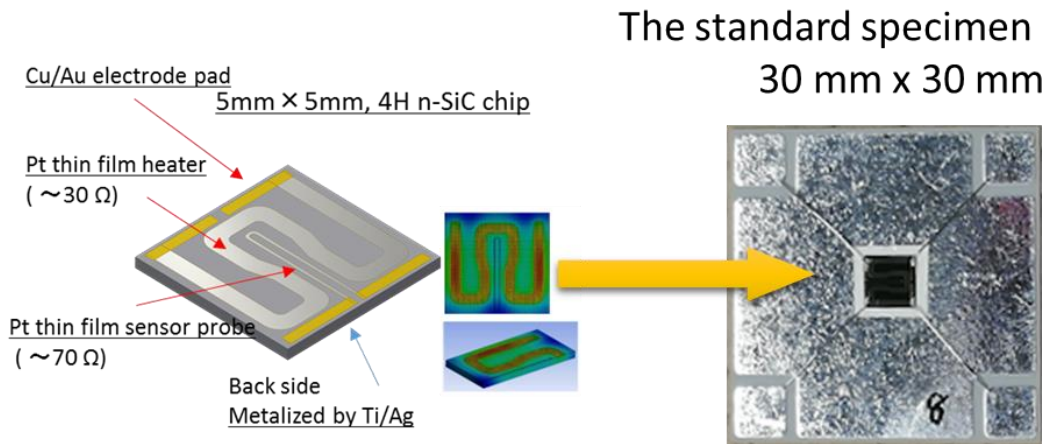
- The method is under discussion at ISO TC206.



$$R_{th} = (T_j - T_h) / Q$$

$$R_{th} = \Delta T / Q$$

- SiC micro heater chip improves the accuracy of R_{th}



- This machine is under development in Yamato Scientific Co., Ltd.

